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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
09/651,386	08/29/2000	ZHIPING YIN	11675.165.2	9675	
22901 7	590 05/21/2002				
JESUS JUANOS I TIMONEDA 1000 EAGLE GATE TOWER 60 EAST SOUTH TEMPLE			EXAMINER		
			QUACH, TUAN N		
SALT LAKE CITY, UT 84111			ART UNIT	PAPER NUMBER	
			2814		
			ATE MAILED: 05/21/2002		

Please find below and/or attached an Office communication concerning this application or proceeding.

		Applicati	n No.	Applicant(s)	/	
Office Action Summary		09/651,386 YIN ET AL.		YIN ET AL.	·	
		Examiner		Art Unit		
•		Tuan Qua	ch	2814		
1 Period for F	The MAILING DATE of this communication ap Reply	pears on the	covershe tw	ith the correspondence addres	s	
THE MA - Extension after SIX - If the per - If NO per - Failure to - Any reply	RTENED STATUTORY PERIOD FOR REPLALLING DATE OF THIS COMMUNICATION. (6) MONTHS from the mailing date of this communication. (6) MONTHS from the mailing date of this communication. (7) Industrial the specified above is less than thirty (30) days, a repriod for reply is specified above, the maximum statutory period or reply within the set or extended period for reply will, by statute or received by the Office later than three months after the mailing atent term adjustment. See 37 CFR 1.704(b).	136(a). In no ever ly within the statut will apply and will e, cause the applic	nt, however, may a cory minimum of thi expire SIX (6) MO cation to become A	reply be timely filed thy (30) days will be considered timely. NTHS from the mailing date of this communing the control of the community of the control of the co	nication.	
1)⊠ F	Responsive to communication(s) filed on 13	February 20	<u>02</u> .			
2a)⊠ T	his action is FINAL. 2b) TI	nis action is i	non-final.			
	Since this application is in condition for allow closed in accordance with the practice under of Claims				erits is	
4)⊠ CI	aim(s) 1-27 is/are pending in the application	n.				
4a) Of the above claim(s) is/are withdra	wn from con	sideration.			
5)∏ CI	aim(s) is/are allowed.					
6)⊠ CI	aim(s) 1-27 is/are rejected.					
7)□ CI	aim(s) is/are objected to.					
8) <u></u> CI	aim(s) are subject to restriction and/o	or election re	quirement.			
Application	Papers					
9)[] Th	e specification is objected to by the Examine	er.				
10)∐ Th	e drawing(s) filed on is/are: a)□ acce	pted or b)	objected to by	the Examiner.		
	Applicant may not request that any objection to the					
11) [The	e proposed drawing correction filed on	_ is: a)∏ ap	proved b)	disapproved by the Examiner.		
Ì	f approved, corrected drawings are required in re	ply to this Offi	ce action.			
12) The	e oath or declaration is objected to by the Ex	kaminer.				
Priority und	ier 35 U.S.C. §§ 119 and 120					
13) 🗌 Ad	cknowledgment is made of a claim for foreig	n priority und	ler 35 U.S.C.	§ 119(a)-(d) or (f).		
a) 🔲	All b)☐ Some * c)☐ None of:					
1.	Certified copies of the priority document	ts have been	received.			
2.	Certified copies of the priority document	ts have been	received in A	Application No		
	Copies of the certified copies of the price application from the International But the Company of the Company o	ıreau (PCT F	Rule 17.2(a)).		е	
	the attached detailed Office action for a list		•		1:4:X	
	nowledgment is made of a claim for domest	• •		•	ncation).	
15)∐ Acl	☐ The translation of the foreign language pro knowledgment is made of a claim for domes					
Attachment(s)						
2) Notice of	f References Cited (PTO-892) f Draftsperson's Patent Drawing Review (PTO-948) ion Disclosure Statement(s) (PTO-1449) Paper No(s) 6	/ ì.		Summary (PTO-413) Paper No(s) Informal Patent Application (PTO-152		

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DETAILED ACTION

The nonstatutory double patenting rejection is based on a judicially created doctrine grounded in public policy (a policy reflected in the statute) so as to prevent the unjustified or improper timewise extension of the "right to exclude" granted by a patent and to prevent possible harassment by multiple assignees. See *In re Goodman*, 11 F.3d 1046, 29 USPQ2d 2010 (Fed. Cir. 1993); *In re Longi*, 759 F.2d 887, 225 USPQ 645 (Fed. Cir. 1985); *In re Van Ornum*, 686 F.2d 937, 214 USPQ 761 (CCPA 1982); *In re Vogel*, 422 F.2d 438, 164 USPQ 619 (CCPA 1970); and, *In re Thorington*, 418 F.2d 528, 163 USPQ 644 (CCPA 1969).

A timely filed terminal disclaimer in compliance with 37 CFR 1.321(c) may be used to overcome an actual or provisional rejection based on a nonstatutory double patenting ground provided the conflicting application or patent is shown to be commonly owned with this application. See 37 CFR 1.130(b).

Effective January 1, 1994, a registered attorney or agent of record may sign a terminal disclaimer. A terminal disclaimer signed by the assignee must fully comply with 37 CFR 3.73(b).

Claims 1-27 are rejected under the judicially created doctrine of obviousness-type double patenting as being unpatentable over claims 1-46 of U.S. Patent No. 6,150,257. Although the conflicting claims are not identical, they are not patentably distinct from each other because the claimed features of the instant claims are encompassed in the claims of '257 including respective dependent claims with the instant claims are broadened in scope, e.g., electrical device instead of semiconductor device in claims 1 and 6, heating rather than heating at less than in claim 2 versus claim 4 of '257, the passivation including chemical reaction products and solid solutions mixture in claim 10 corresponding to the passivation claimed in '257 by reacting with the chemical position, the process including titanium liner, titanium nitride and tungsten plug or metallitc structure and the passivation layer of tungsten nitride in claims 15-25 corrresponds to the process claimed in claim 42 of '257 with broader scope, the newly added claims 26 and 27 regarding nitrogen-containing silane correspond to well known

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alternative compositions to ammonia for nitrogen source such as ammonia, diatomic nitrogen, nitrogen containing silane and the like, as admitted on page 6 lines 12-15, such selection of well known alternative materials thus would have been obvious and would have been within the purview of one skilled in the art.

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to

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consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

Claim 1, 2, and 5-27 are rejected under 35 U.S.C. 103(a) as being unpatentable over lijima et al. taken with Hu.

lijima et al. teach providing opening in insulating film 32, filling with conductive films 33/34/35, removing portions of the conductive films outside the opening to form conductive plug in the opening, annealing in nitrogen atmosphere to nitrify the surface of layer 35. The provision of upper insulating layer 37 is also shown. See column 7 line 63 to column 8 line 43, column 10 lines 10-14 and 29-43. An alternative process employs forming opening in insulating layer 82, depositing conductive layer 84, forming plug filling the opening, annealing in nitrogen to form layer 84b, depositing second insulating layer thereon. See column 15 lines 30-64. The limitation regarding the dielectric layer adhered to the conductive layer and the passivation layer by chemical reaction or including chemical reactions and/or solid solutionsw would be met, absent evidence to the contrary, and as shown in lijima et al. and any reaction between the dielectric and the nitriding layer would take place due the proximity of the layers. Furthermore, Hu et al. teach the inclusion of tungsten nitride barrier 12 on tungsten plug 14 in an insulating layer wherein the tungsten nitride can be formed by light nitridation of tungsten including the plasma nitridation, e.g., in environment containing nitrogen and plasma thereof to form effective diffusion barrier. See Fig. 1, column 2 lines 13-28, column 3 lines 5-8, column 7 line 65 to column 8 line 18. In addition to the reasons delineated in lijima et al. above, it would have been further obvious to have effected the

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light nitridation of the conductive plug in lijima et al. wherein effective barrier thereon would be obtained as suggested by Hu et al. It would have been conventional and would have been within the purview of one skilled in the art to have selected appropriate and suitable layer thicknesses, and conventional nitrogen containing plasma such as ammonia; the newly added claims 26 and 27 regarding nitrogen-containing silane correspond to well known alternative compositions to ammonia for nitrogen source such as ammonia, diatomic nitrogen, nitrogen containing silane and the like, as admitted on page 6 lines 12-15, such selection of well known alternative materials thus would have been obvious and would have been within the purview of one skilled in the art.

Claims 3 and 4 are rejected under 35 U.S.C. 103(a) as being unpatentable over lijima et al. taken with Hu as applied to claims 1, 2, and 5-27 above, and further in view of Aoyama et al.

The references as applied above do not recite insitu deposition.

Aoyama et al. teach the use of apparatus allowing the processing including plasma nitridation and interlayer insulator deposition without exposure of the wafers to the atmosphere. See Fig. 35, column 29 line 36 to column 30 line 13.

It would have been obvious and would have been within the purview of one skilled in the art to have effected the processing above including in-situ deposition of the upper insulating layer in a desired processing sequence together with or immediately following the formation of the nitride film without exposure to the atmosphere since such is conventional and advantageous to avoid interaction between the atmosphere and the previously formed film.

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Applicant's arguments filed February 13, 2002 have been fully considered but they are not persuasive.

Applicant argues that lijima et al. does not teach the passivation sufficiently thicken to resist formation of the oxide husk yet does not prevent the second dielectric layer from adhering to the second conductive layer and that additional steps not required in the instant applications would be required. Applicant nonetheless has failed to show that the adhesion of the dielectric to the conductive layer would not take place in lijima et al. and that the chemical reactions would not take place due to the proximity between the dielectric layer and the nitriding layer. It remains that such layers would be apparent due to the proximity thereof. In addition, the light nitridation in lijima would have been obvious and advantageous as evidenced by Hu et al. wherein effective barrier would be obtained.

Applicant argues that Hu employs a different order by building a stack that is later exposed, instead of forming a depression. This does not consider the teaching of tungsten 14 in insulating layer and the formation of tungsten nitride layer on the plug. It remains further apparent that such opening formation and filling with conductive plug therein is well known in the art and does not require any inventiveness. The provision of the opening in an insulating layer 82 followed by conductive layer 84 to form plug and annealing in nitrogen is also shown in lijima et al., see column 15 lines 30-64.

Applicant argues that the thickness of less than 50 Å or 2 to 20 Å is not explicitly recited. To the extent that such thickness is critical they should be incorporated into the claims, particularly claims 1, 10, and 16 which are silent regarding any thickness

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required. The selection of such non-critical thickness would have been one that is normally within the purview of one skilled in the art and would have been a matter of routine experimentation and optimization.

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to examiner Quach whose telephone number is 703-308-1096. The examiner can normally be reached on M - F from 8:30 to 5.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri, can be reached on (703) 306-2794. The fax phone number for the organization where this application or proceeding is assigned is 703-308-7722.

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Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

Tuan Quach Primary Examiner